

SEMICAPS 4000

INVERTED ANALYTICAL AND TESTER-DOCKED SYSTEM



Features

Tester-Docked Conversion

- Analytical or ATE docked configuration
- 300 mm wafer stage including auto-lock compatible with Probe Cards and manipulators
- Docks easily to Tester or Probe Station
- High resolution stage with 0.5 μm repeatability
- Aplanatic Refractive Solid Immersion Lens (ARSIL) option, currently probing 3nm nodes
- CAD interface option
- Techniques include a combination of:
 - Laser Timing Probe (LTP)
 - Scanning Optical Microscopy (SOM) with best sensitivity
 - static: TIVA, OBIRCH
 - dynamic: LADA, SDL
 - Photon Emission Microscopy (PEM) with various options for the InGaAs or Si-CCD camera
 - Thermal Microscopy (THM) with InSb camera